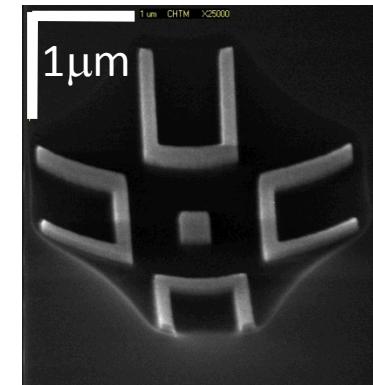
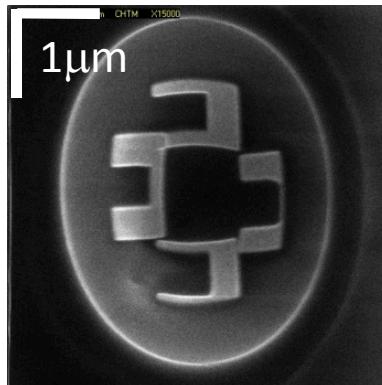




Metamaterials Science & Technology

SAND2010-0217C

3-D Metamaterial Fabrication Using Membrane Projection Lithography



D. Bruce Burckel, P. Davids, I. Brener, G. A. Ten Eyck,
A. R. Ellis, J. R. Wendt, and M. B. Sinclair

dbburck@sandia.gov



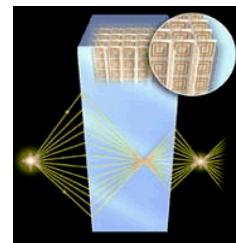
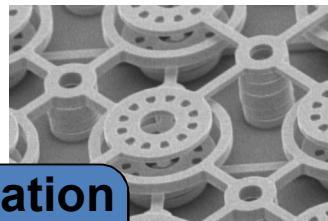
Sandia is a multiprogram laboratory operated by Sandia Corporation, a Lockheed Martin Company,
for the United States Department of Energy's National Nuclear Security Administration
under contract DE-AC04-94AL85000.





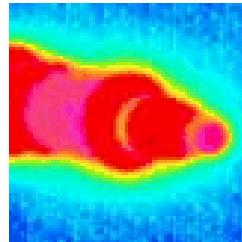
Metamaterials Science & Technology

Sandia's MST Program at a Glance



fabrication & testing

- DUVL, EBL, PnP, NIL
- spectroscopic phase meas.



- thermal IR
- limits to shorter- λ

low loss

Metamaterials

IR
8-12 μ m

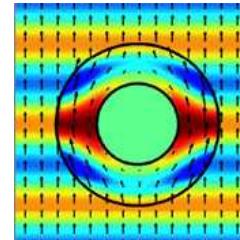
3D

materials science

- dielectrics/composites/alloys
- low- n polymer 3D matrix materials

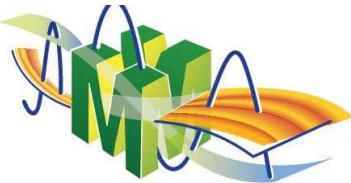
- <0.1 db/Wave
- perfectly absorbing structures

theory & modeling



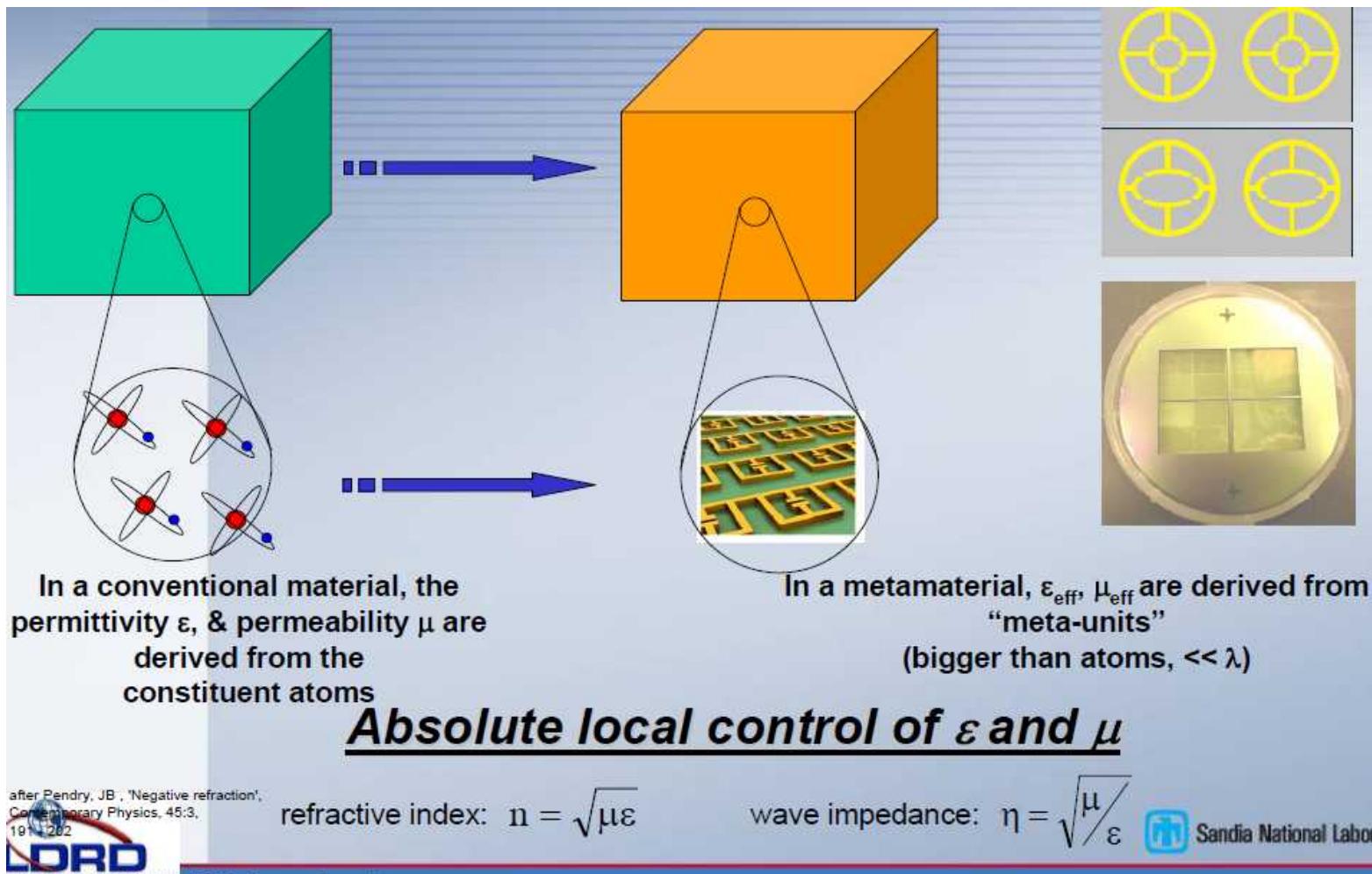
university Partners

- volumetric energy flow, large area
- multiple directions
- multiple polarizations



Metamaterials Science & Technology

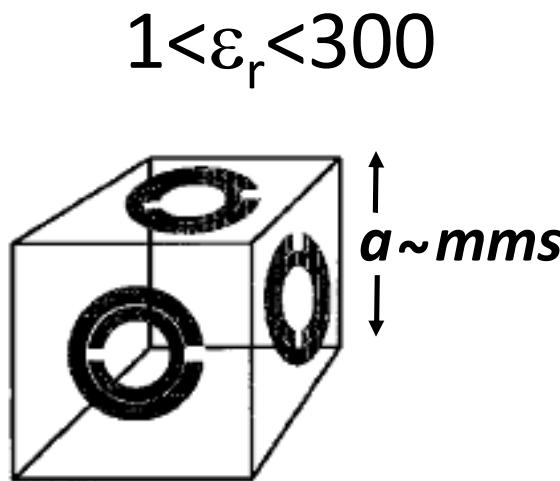
Concept of Metamaterials



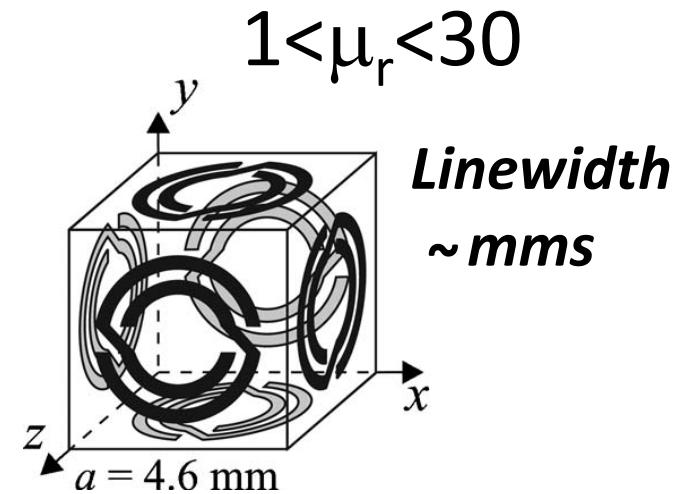


Metamaterials Science & Technology

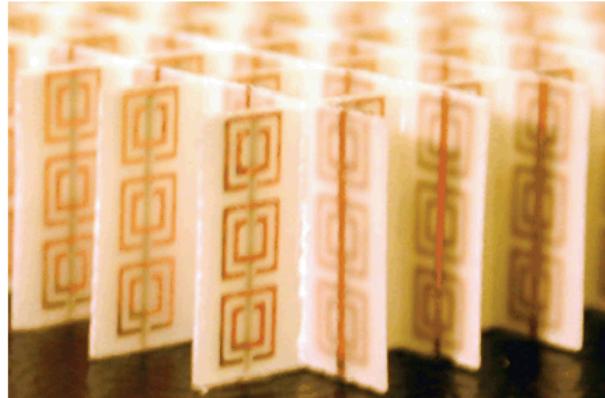
Notional Design



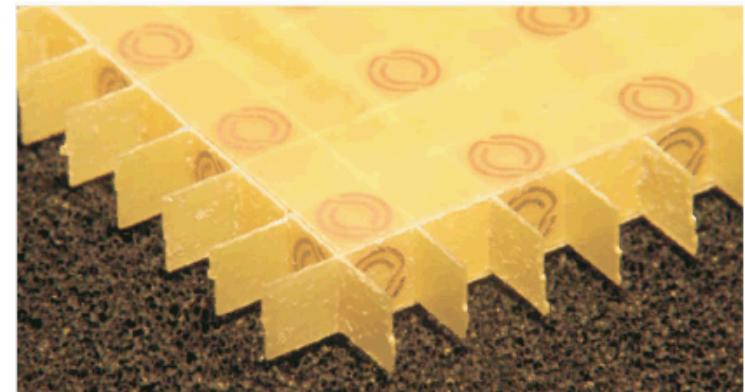
Pendry, IEEE Trans on Microwave Theory and Techniques
47, #11, 2075 (1999)



Baena, APL 91, 191105, (2007)



Schultz, Science 292, 77, (2001)



Baena, APL 91, 191105, (2007)

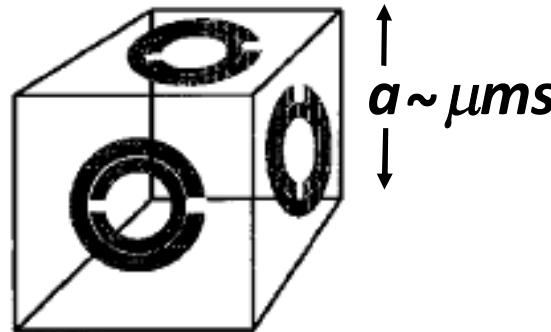
Experiment



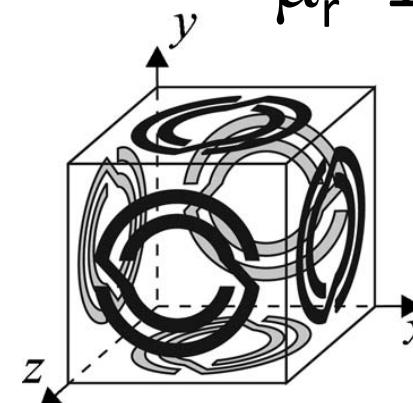
Metamaterials Science & Technology

RF/ μ Wave Designs \rightarrow IR/Optical

$$1 < \epsilon_r < 40$$



$$\mu_r = 1$$

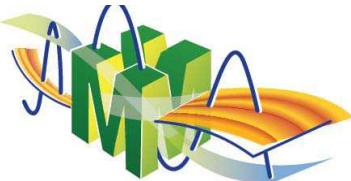


Material Challenges

- Maximum ϵ_r and μ_r are OOM smaller than for RF frequencies
- Metals become lossy at IR and optical frequencies

Fabrication Challenges

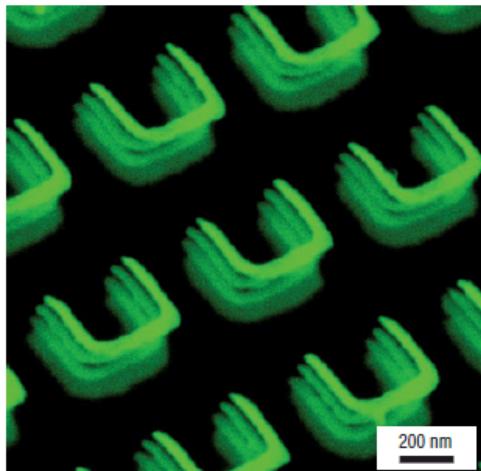
- Linewidths require advanced lithography
- Most advanced lithography techniques have short depth of focus – can only form planar patterns
- Post processing assembly not possible at these size scales – Full resonator must be fabricated in place
- Out-of-plane features are limited in aspect ratio by typical etch/deposition methods



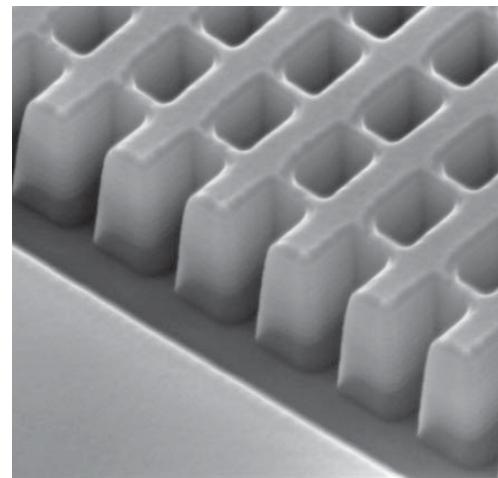
Metamaterials Science & Technology

IR and Optical Metamaterials

Stacked Planar

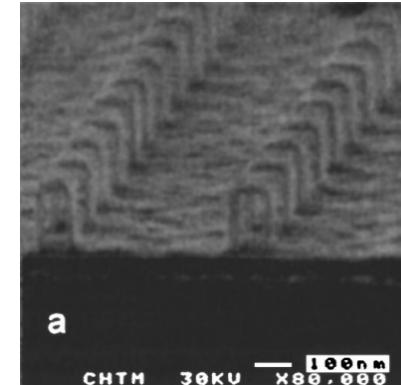


Giessen- Nature Mat **7**, 31, (2008)

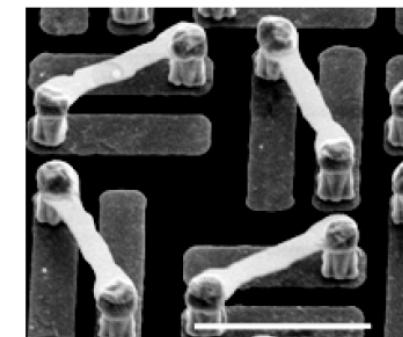


Zhang, Nature **455**, 376 (2008)

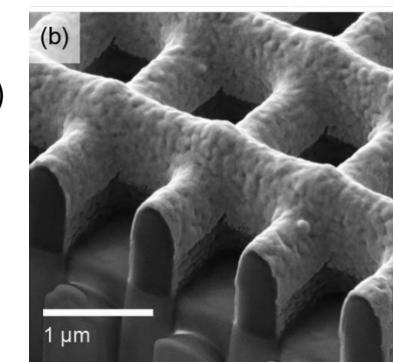
Out-of-Plane Current



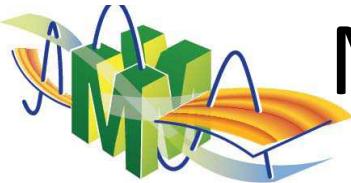
Brueck - JOSA B **23**, #3, 434, (2004)



Zhang, PRL **102**, 023901, (2009)

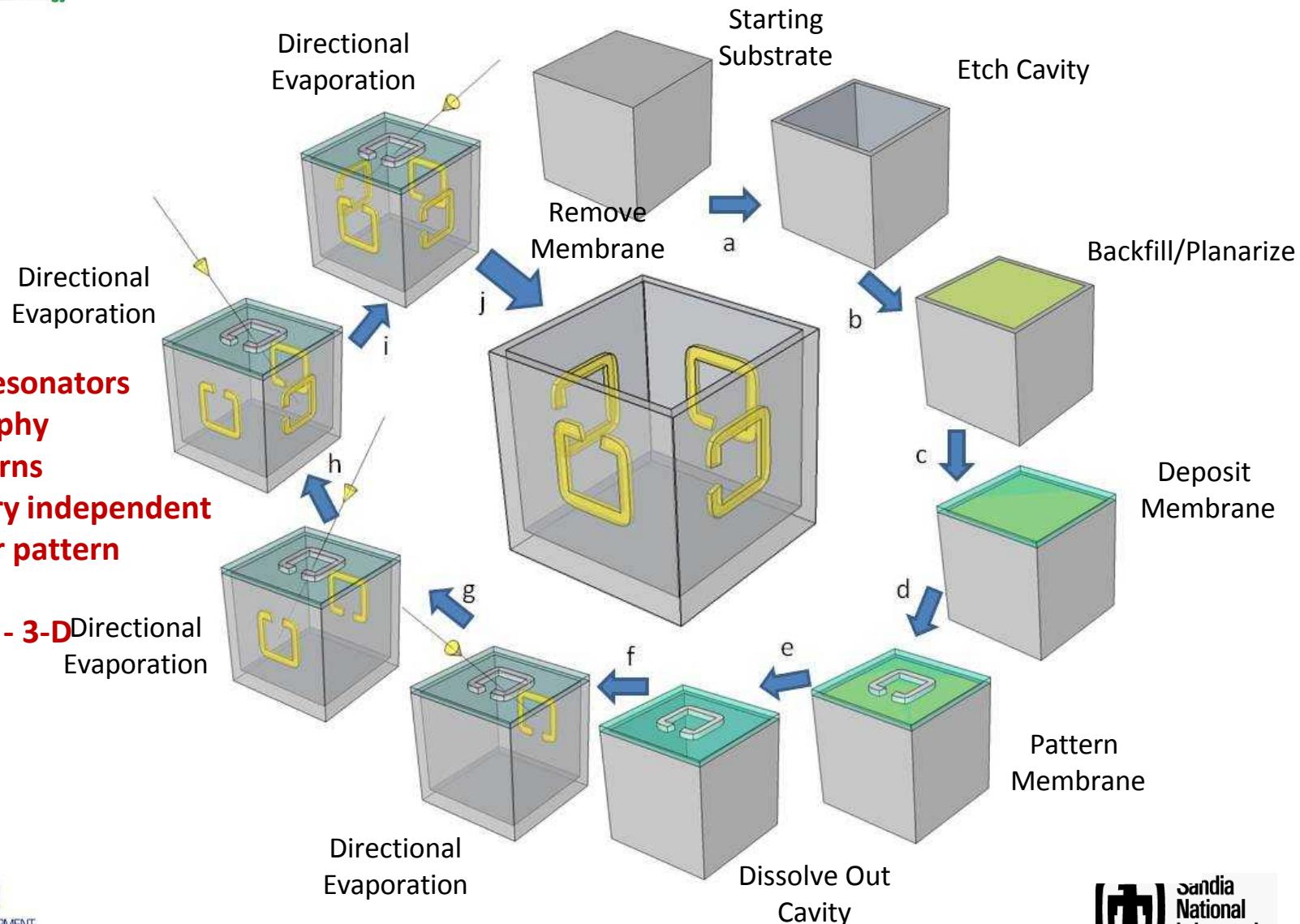


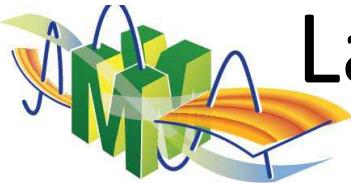
Wegener, Optics Lett **34**, 16, (2009)



Membrane Projection Lithography

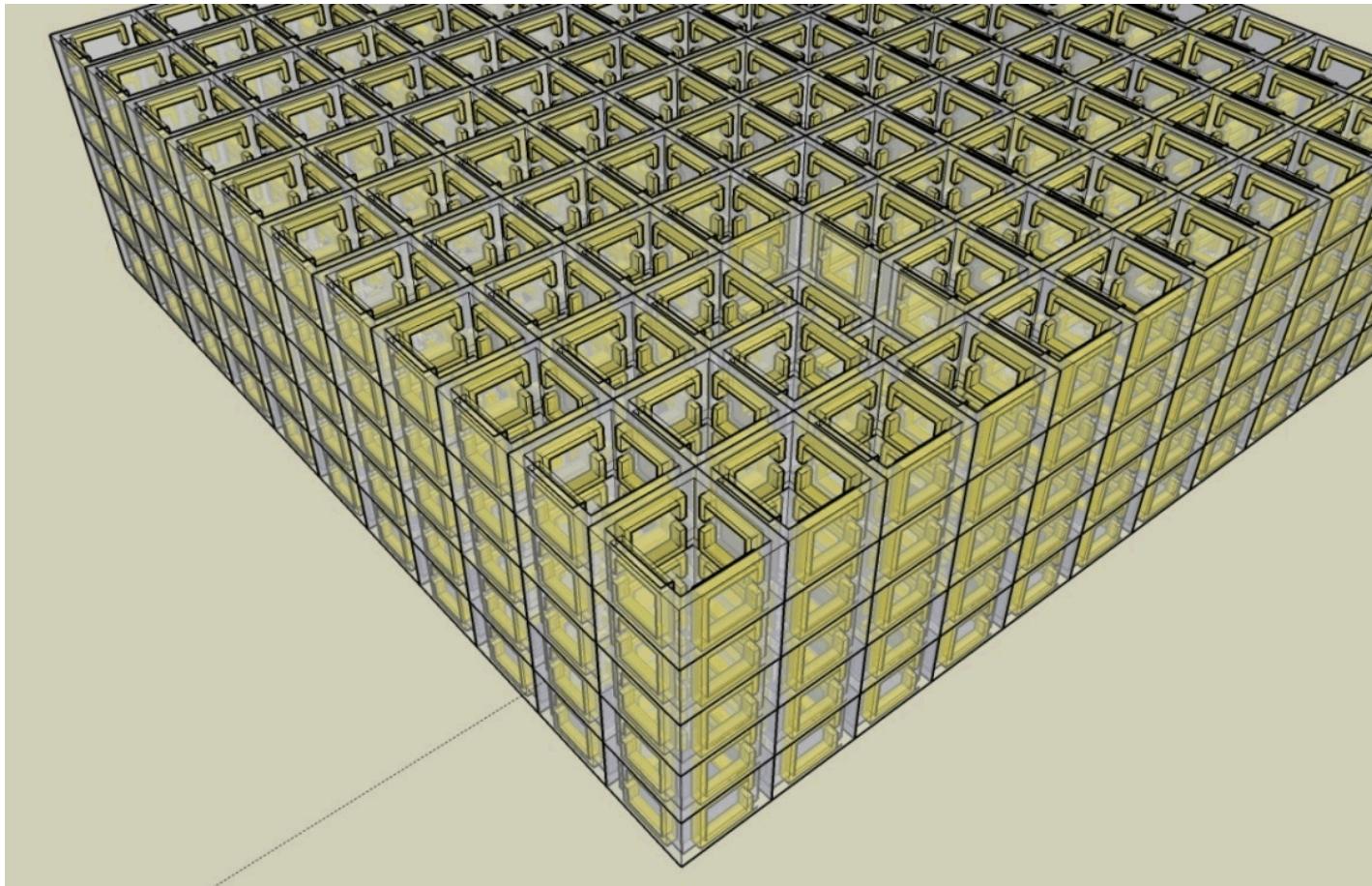
Metamaterials Science & Technology

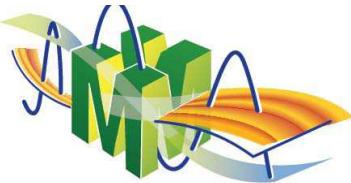




Metamaterials Science & Technology

Layer-by-layer Route To 3D Material

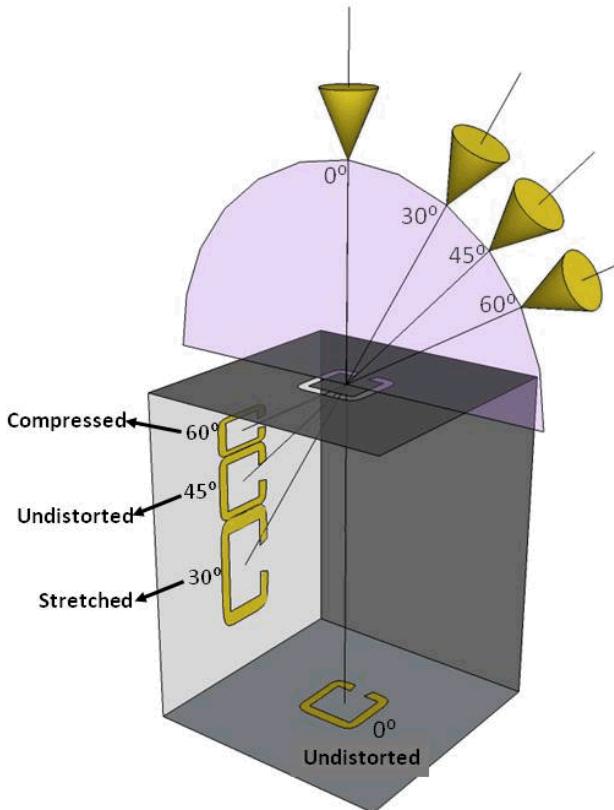




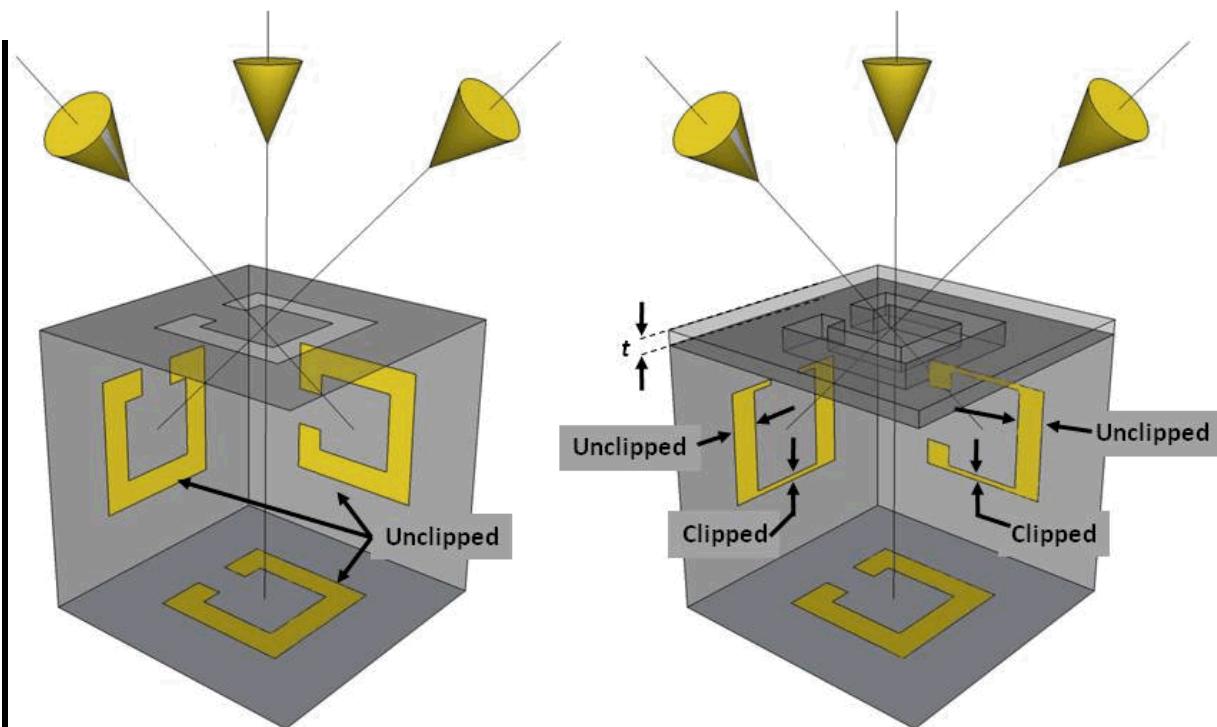
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Real Membranes result in Linewidth Clipping

Projection at 45°
Preserves Pattern
Shape



Real Membranes result in Linewidth Clipping



**Vanishing Thickness
Membrane**

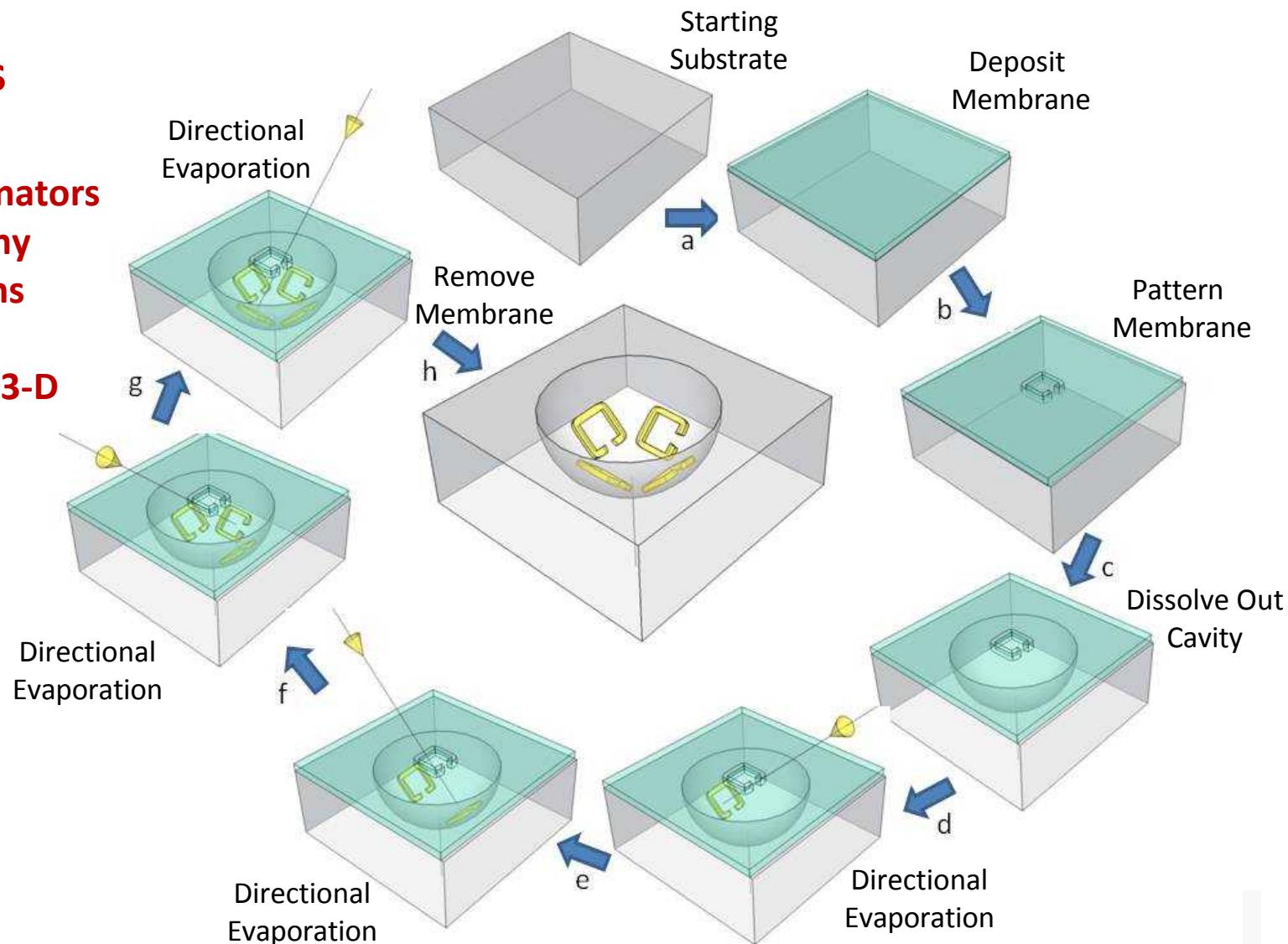
**Finite Thickness
Membrane**



Metamaterials Science & Technology

Advantages

- Self-Aligned
- Non-planar resonators
- Planar lithography
- Arbitrary patterns
- Scalable
- Layer-by-layer - 3-D

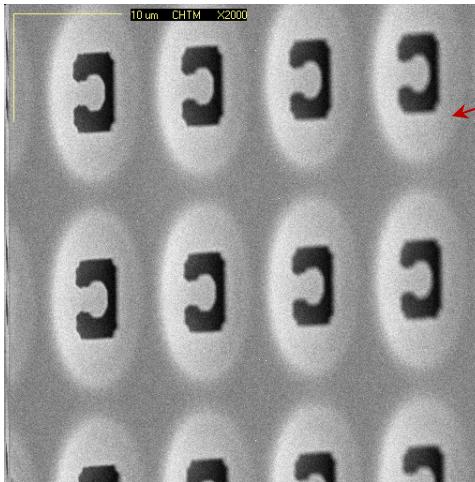




Metamaterials Science & Technology

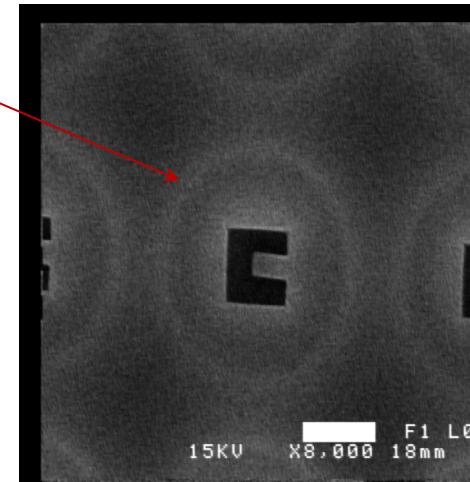
SAMPL – Patterned Membranes

Contact Lithography

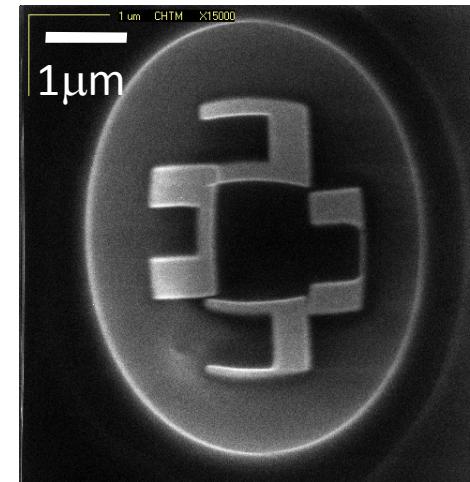
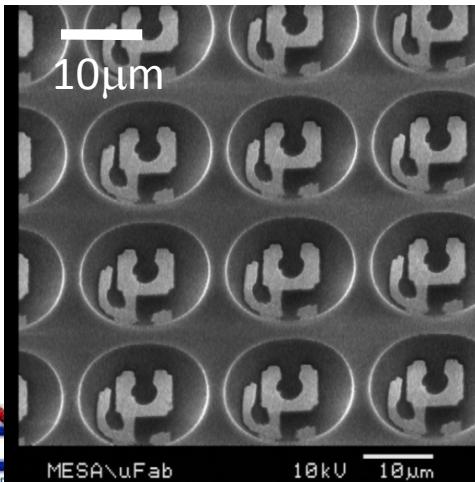


Halos
show
extent
of cavity

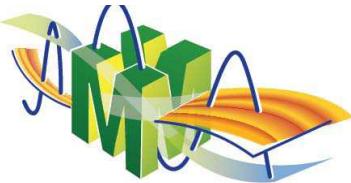
E-Beam Lithography



Suspended
Patterned
Membrane

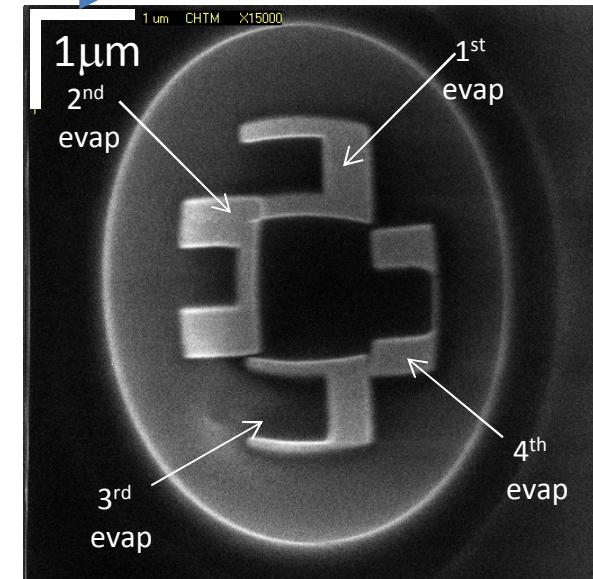
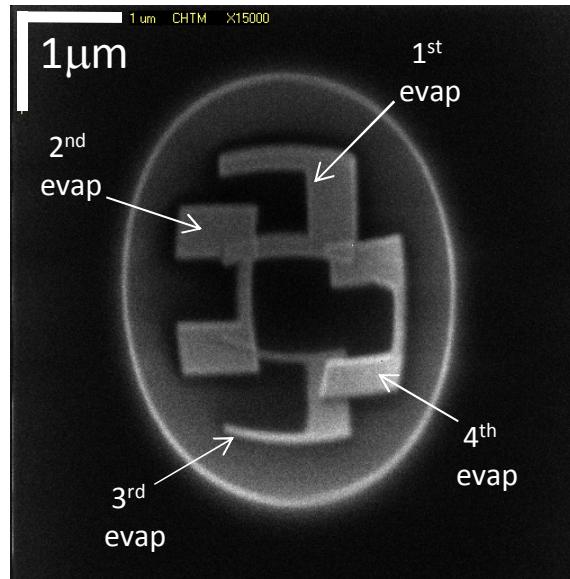
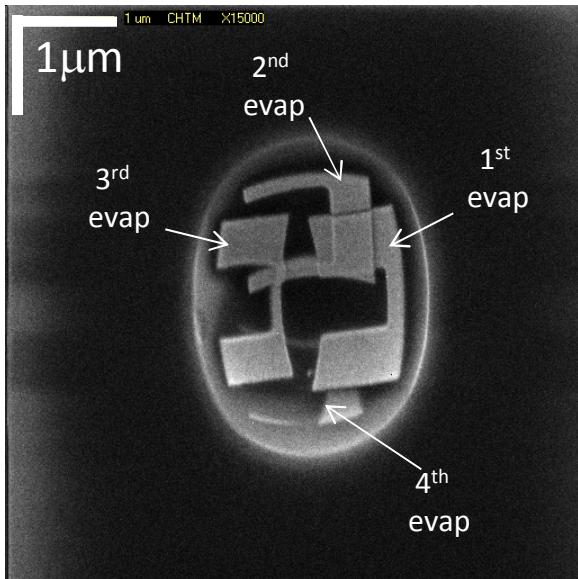


Au-SRRs
After
Liftoff

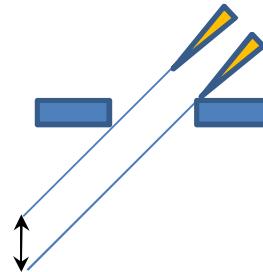


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Curved SRRs via MPL

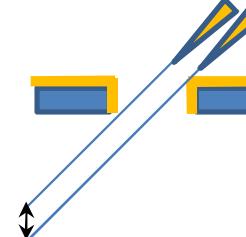


1st Evap



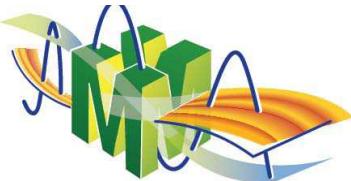
1st Evap linewidth inhomogeneity
due to membrane thickness

4th Evap



4th Evap linewidth inhomogeneity
due to membrane thickness
+ accumulated deposition

240nm total
deposition
through ~340 nm
clear aperture

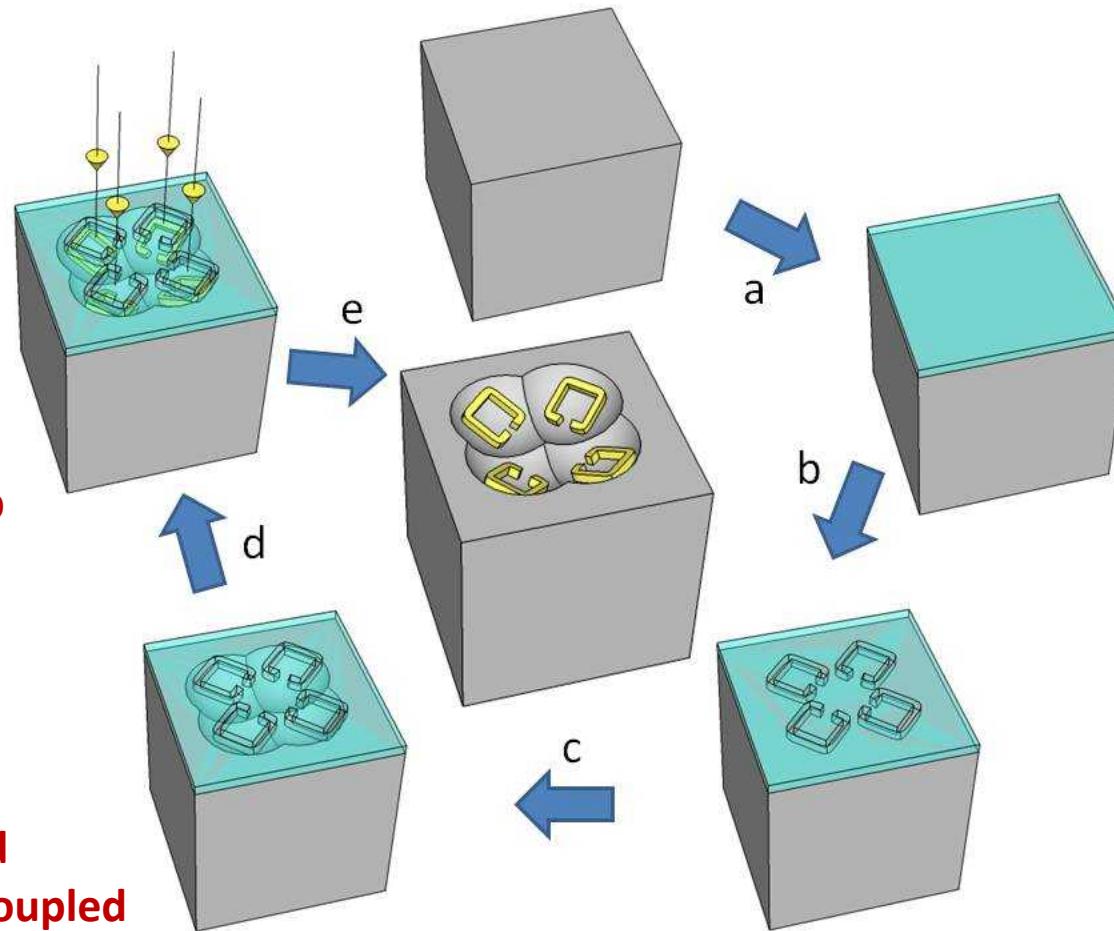


Metamaterials Science & Technology

Single-Evaporation MPL

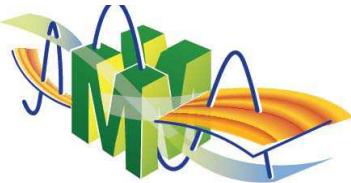
Advantages

- Self-Aligned
- Non-planar resonators
- Planar lithography
- Arbitrary patterns
- Single Evaporation Step
- Scalable
- Layer-by-layer - 3-D

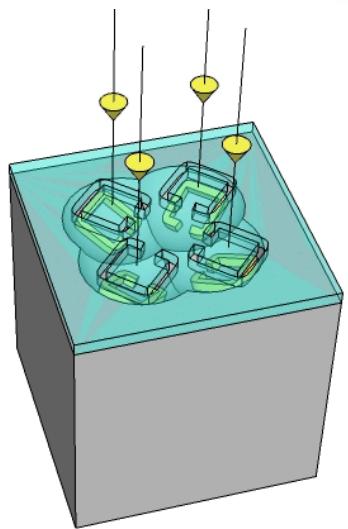


Caveats

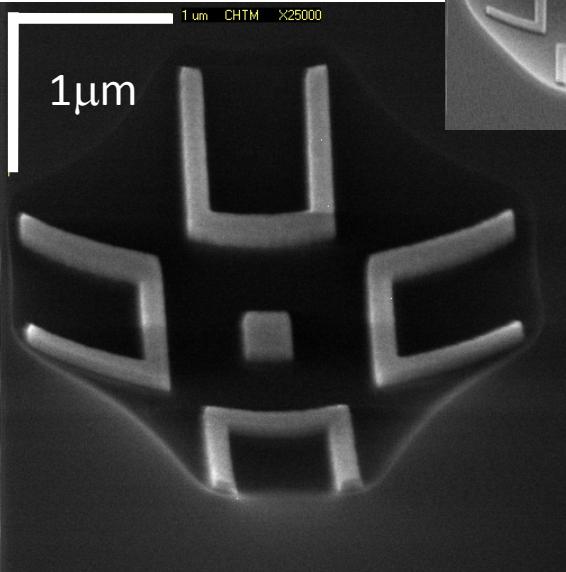
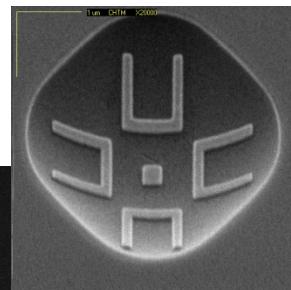
- resonator cavity and pattern are tightly coupled



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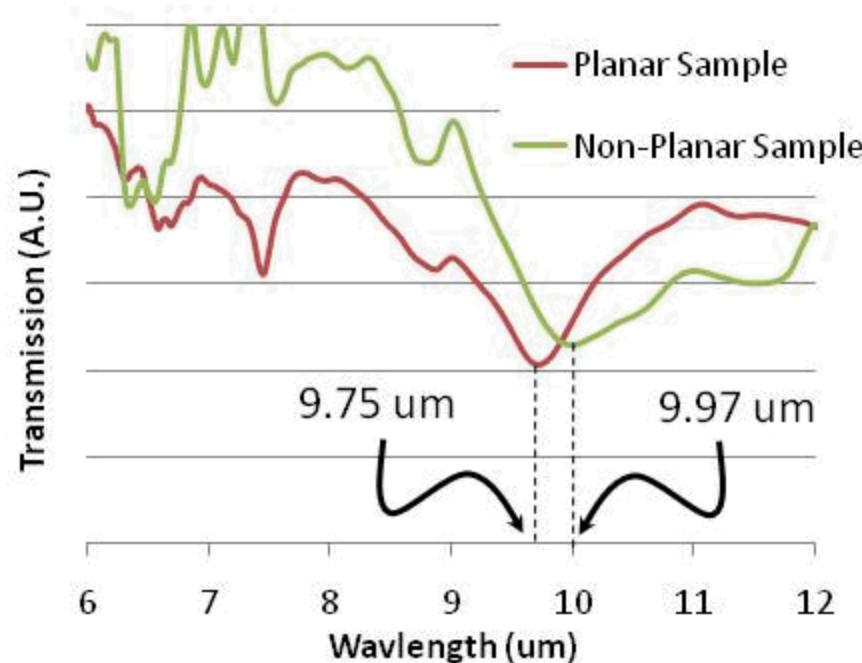


Single Evaporation
Self-Aligned
Membrane
Projection
Lithography



Fabrication of Out-of-Plane MM Resonators

Un-Normalized Normal Incidence
FTIR Transmission Data



Impact of Out-Of-Plane Resonators

1. Resonance shift due to projection of pattern out of plane
2. Resonance broadening.

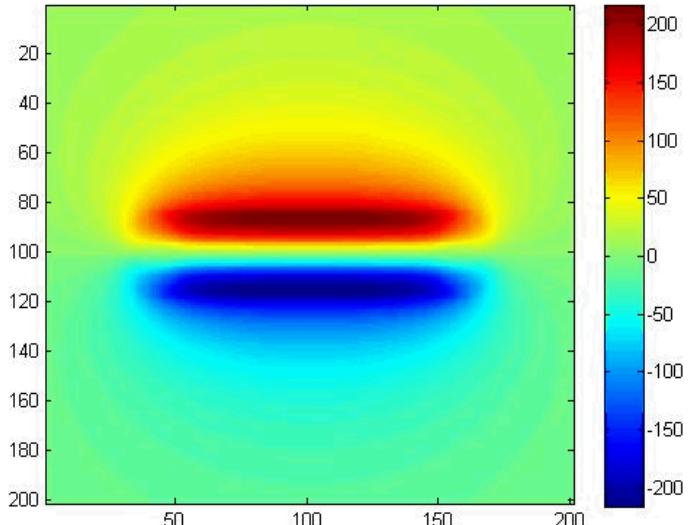


Metamaterials Science & Technology

Calculating Induced Magnetism For A Planar Current Stripe

Magnetic Field

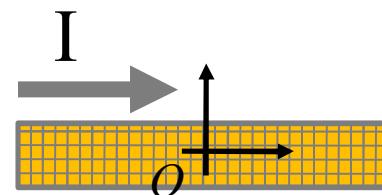
$$B(x, y, z) = \frac{\mu_0 I}{4\pi} \sum \left(\frac{dl' \times \vec{R}}{|R|^3} \right)$$



Magnetization Vector

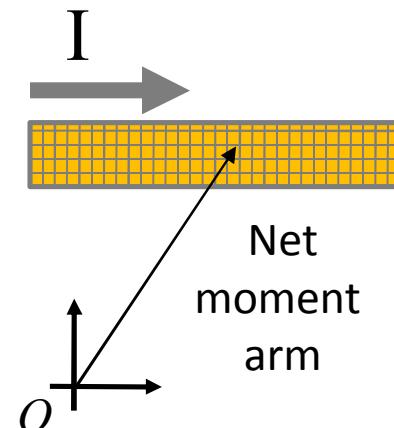
$$\vec{M} \equiv \frac{1}{2c} \sum \vec{r}_i \times \vec{J}_i$$

Origin A:



$$\vec{M} = 0$$

Origin B:



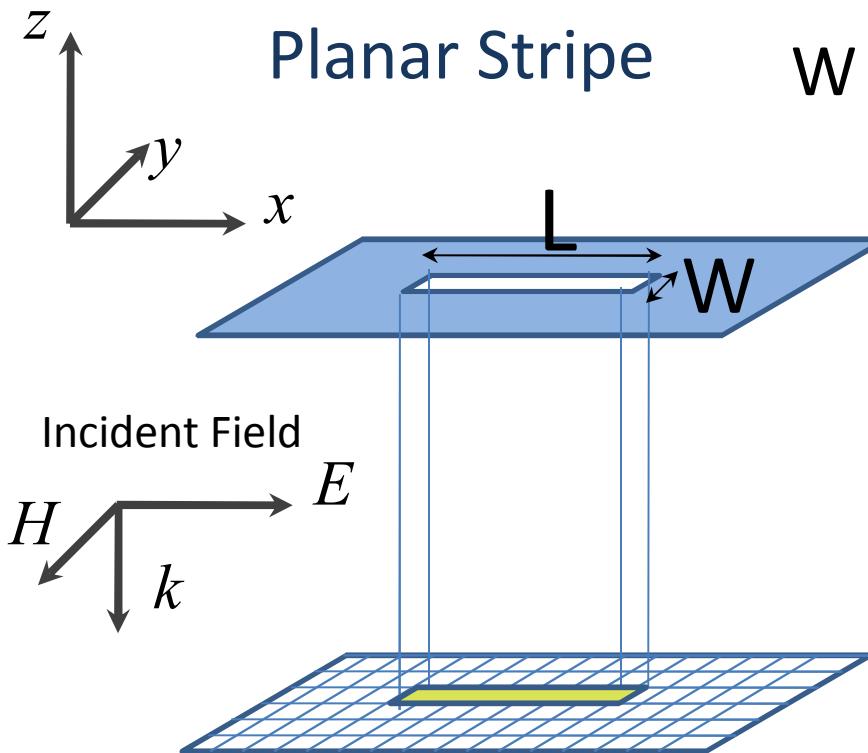
$$\vec{M} \neq 0$$

We will always choose the center of mass coordinate as the origin in this work



Computation Cell for Single Stripe Geometry

Metamaterials Science & Technology



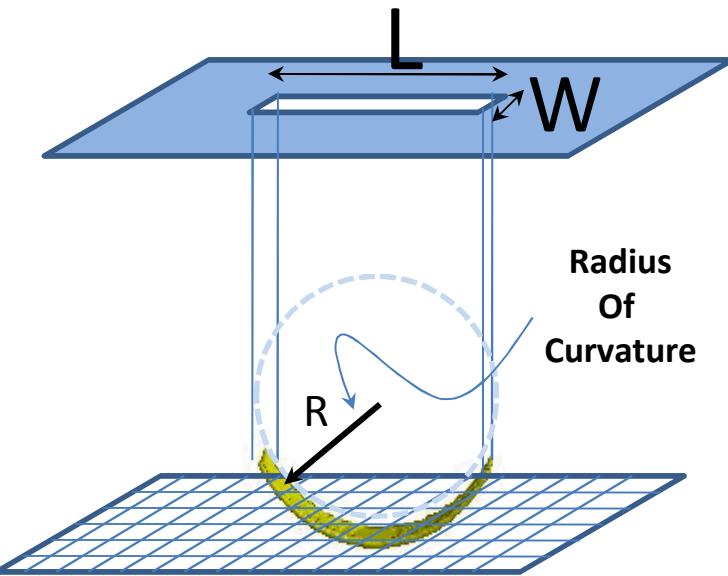
Simplified Current Model:

Assume E-field induces a constant current with only an x-component.

$$L = 1 \mu\text{m}$$

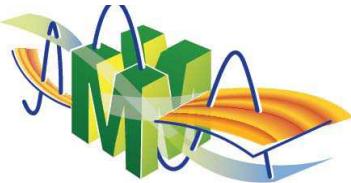
$$W = 0.2 \mu\text{m}$$

Curved Stripe



Simplified Current Model:

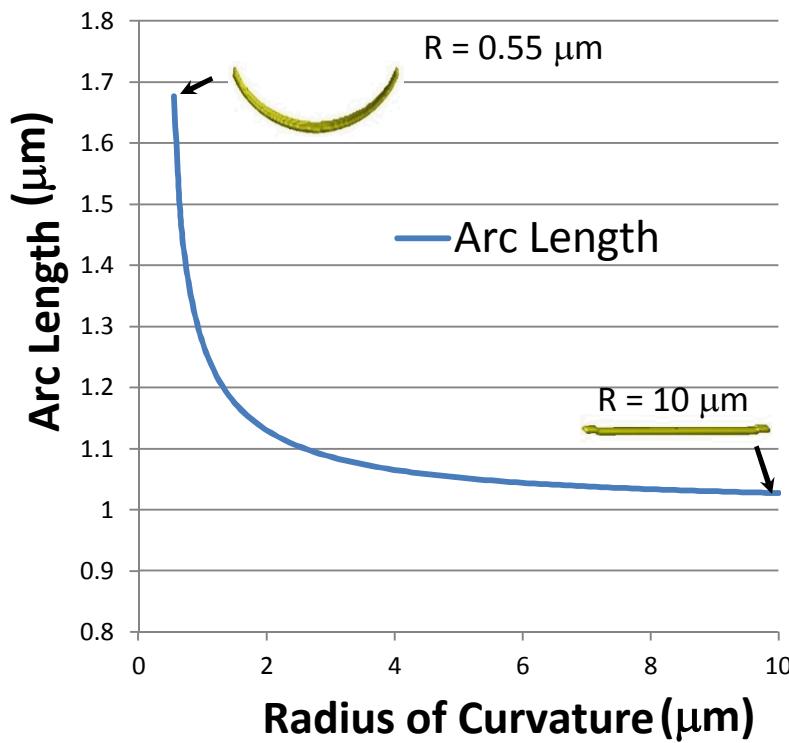
Assume E-field induces a constant current with only an x-component – curvature of metal also creates z-component.



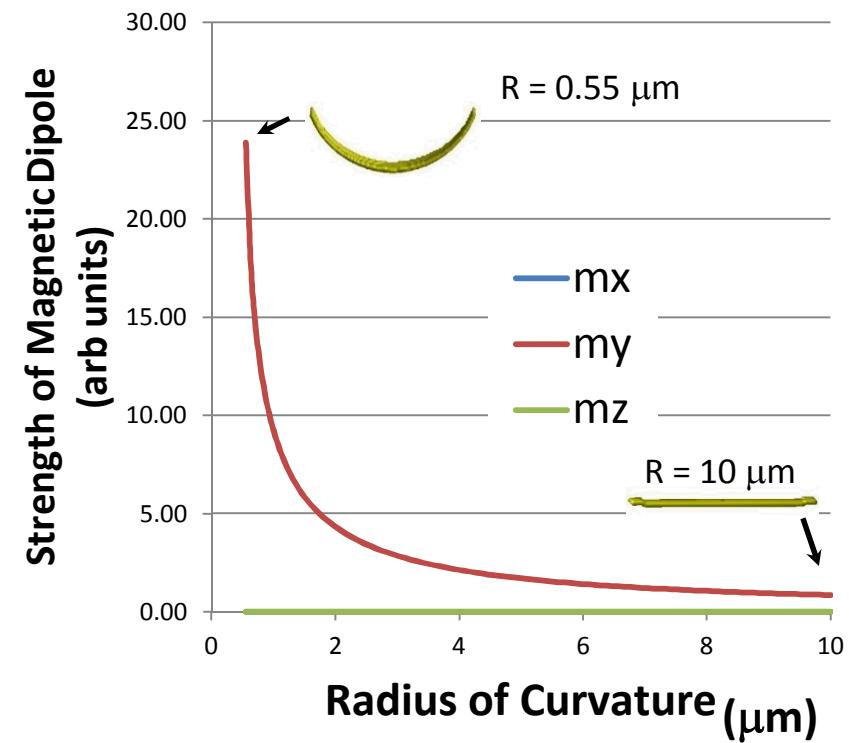
Metamaterials Science & Technology

Effect of Adding Curvature: Single Stripe

Arc Length Dilation



Non-Zero Magnetization



Mask Dimensions:

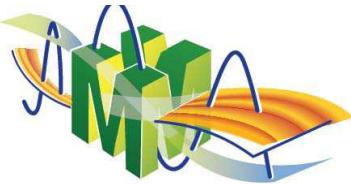


$$\left. \begin{array}{l} L = 1 \text{ } \mu\text{m} \\ W = 0.2 \text{ } \mu\text{m} \end{array} \right\}$$

m_x, m_z are identically 0

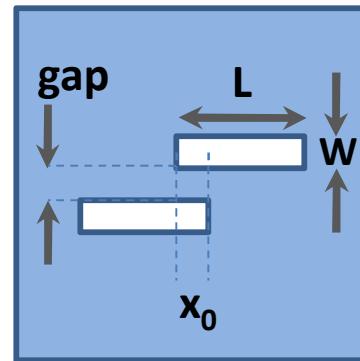
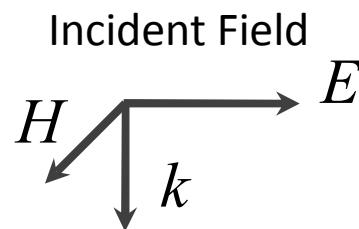


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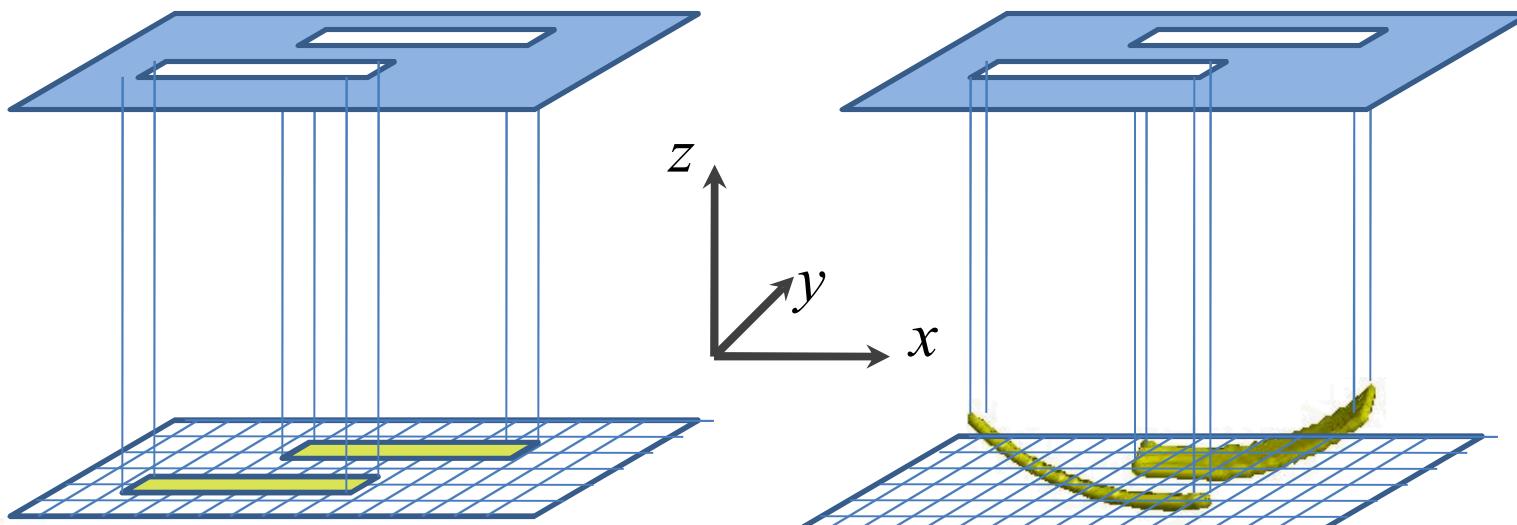


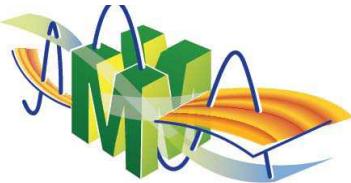
Metamaterials Science & Technology

Computation Cell for Split Wire Pair Geometry



Top-Down
Schematic of
SWP Membrane

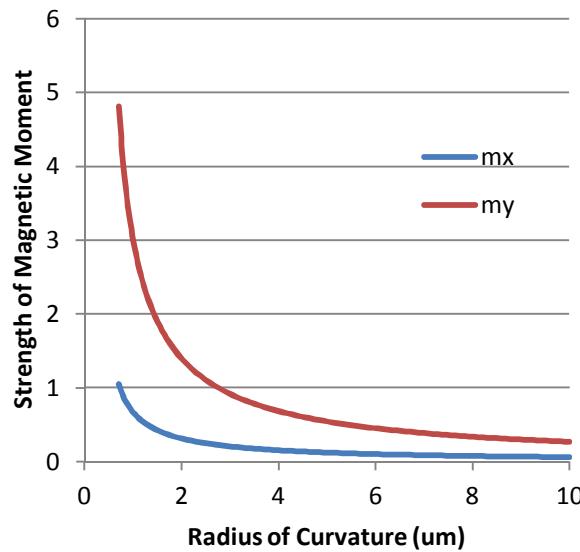




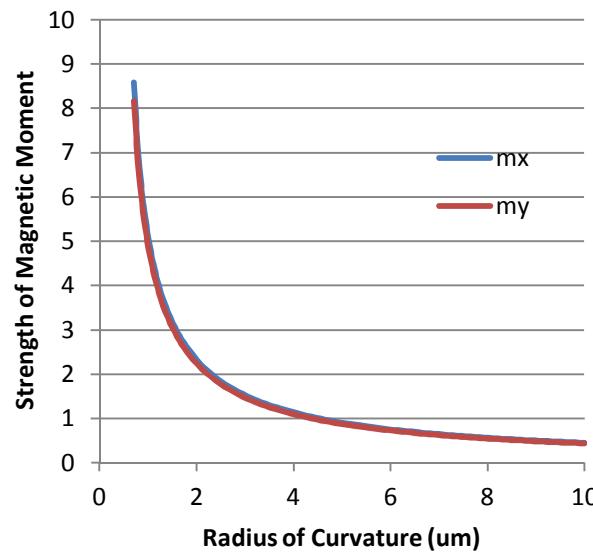
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Effect of Adding Curvature: SWP

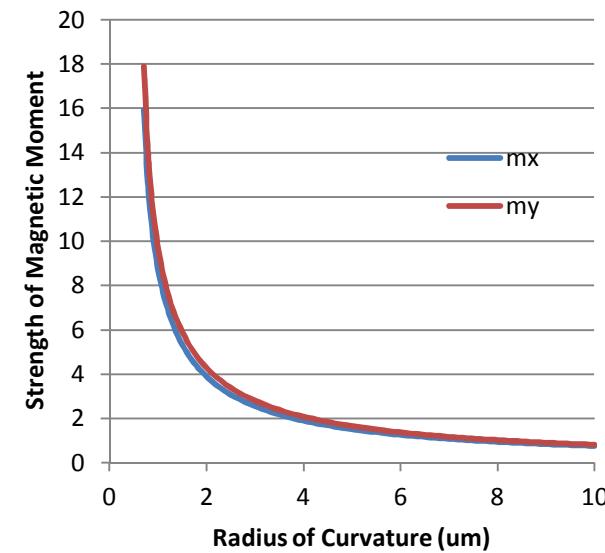
Tunable Non-Zero m_x and m_y



$L = 0.5 \mu\text{m}$
 $W = 0.1 \mu\text{m}$
 $x_0 = 0.0 \mu\text{m}$
gap = $0.05 \mu\text{m}$



$L = 0.5 \mu\text{m}$
 $W = 0.3 \mu\text{m}$
 $x_0 = 0.2 \mu\text{m}$
gap = $0.3 \mu\text{m}$



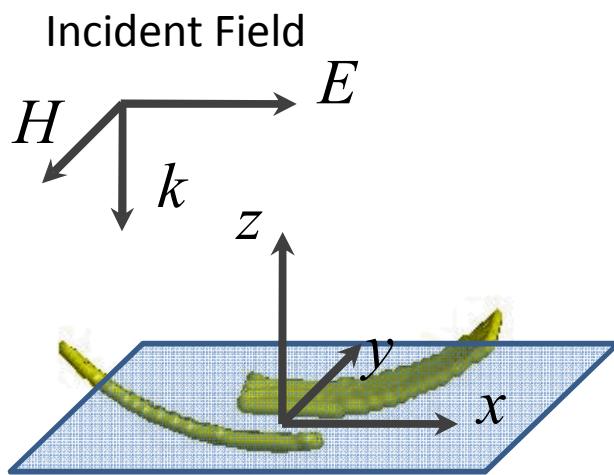
$L = 0.5 \mu\text{m}$
 $W = 0.3 \mu\text{m}$
 $x_0 = 0.0 \mu\text{m}$
gap = $0.3 \mu\text{m}$



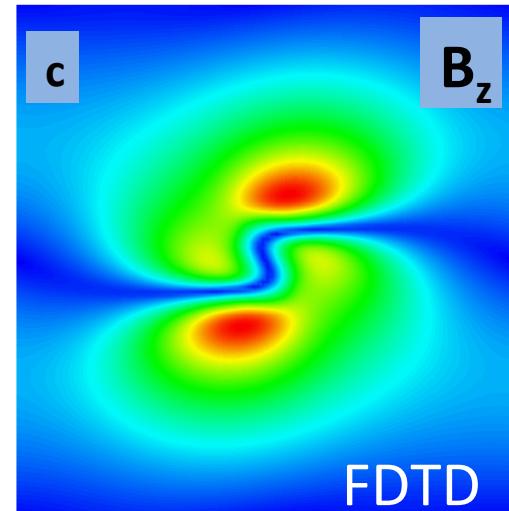
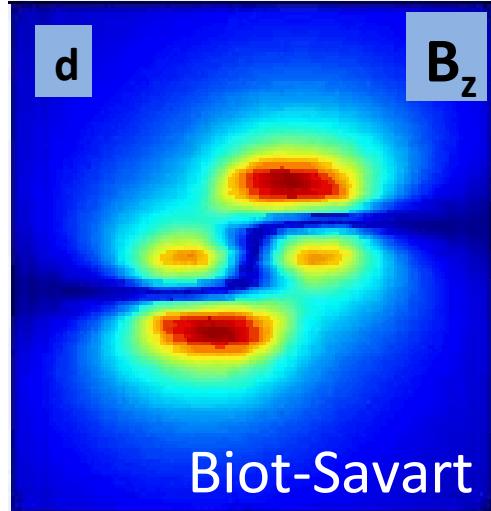
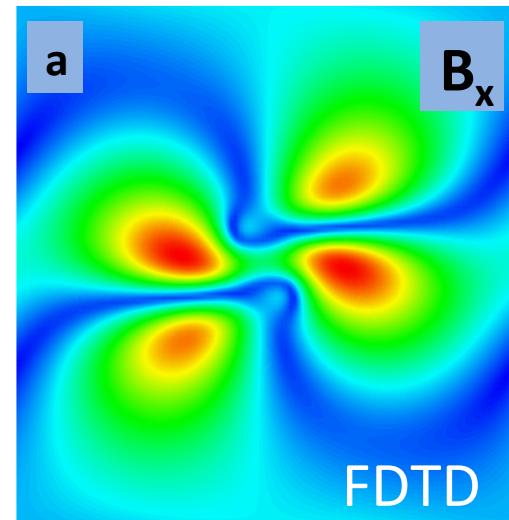
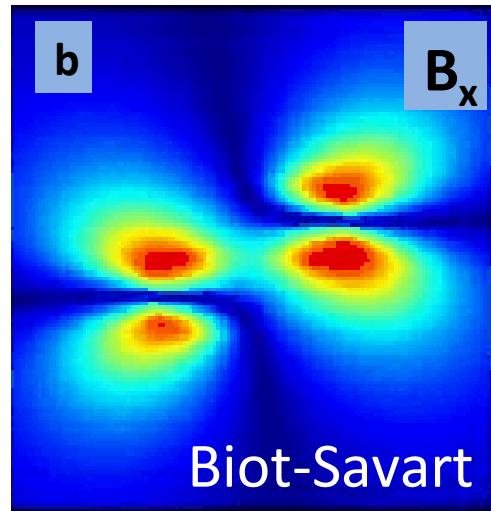
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Simplified Current Model

Biot-Savart vs FDTD



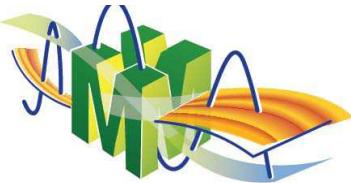
Calculated B-Field
At $z = 0$



Run Time \sim s

Run Time \sim hrs

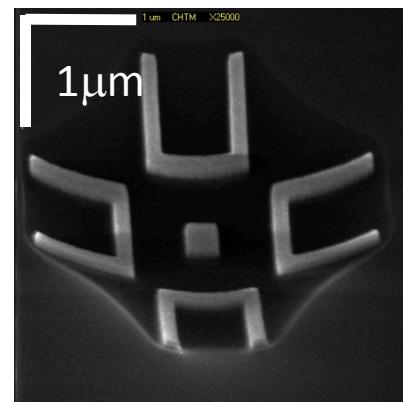
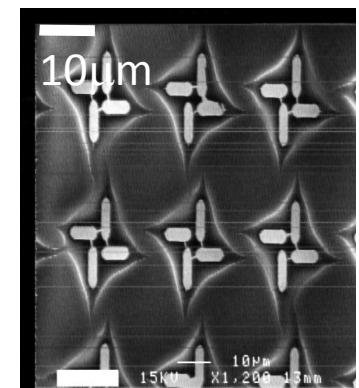
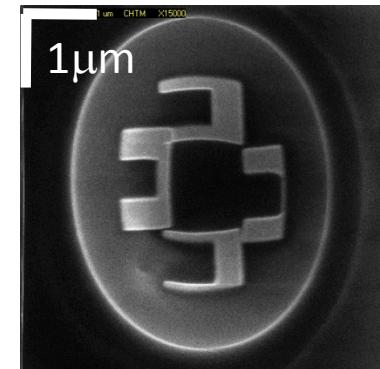
sandia
national
laboratories

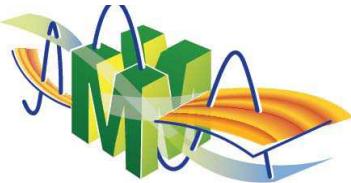


Metamaterials Science & Technology

Closing Thoughts

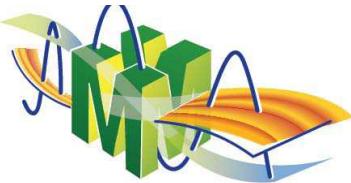
1. MPL offers a fabrication route to 3-D IR/Optical Metamaterials.
2. Vision → Hand crafted unit cells with fully 3-D current flow – leveraging symmetry, geometry and material.
3. Expand modeling and simulation capabilities to develop intuition for design space using MPL.





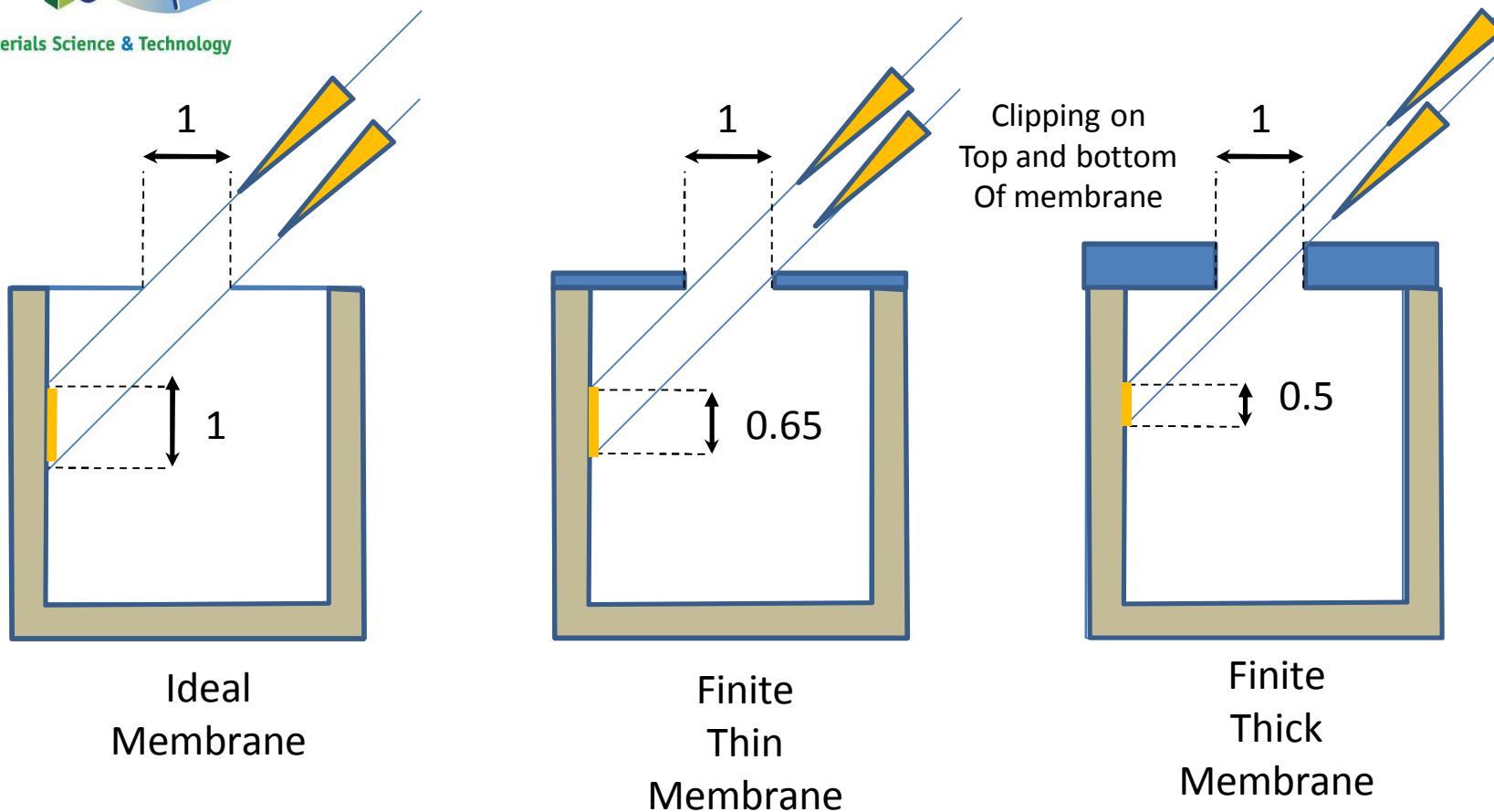
Metamaterials Science & Technology

Backup Slides



Metamaterials Science & Technology

Impact of Membrane Thickness



For evaporation at 45°, projected linewidth is decreased by the thickness of the membrane.

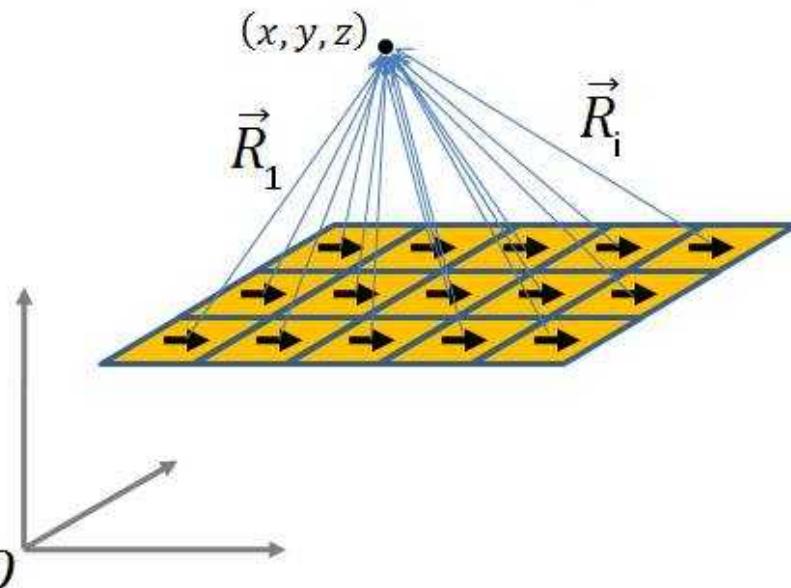


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Induced Magnetic Response

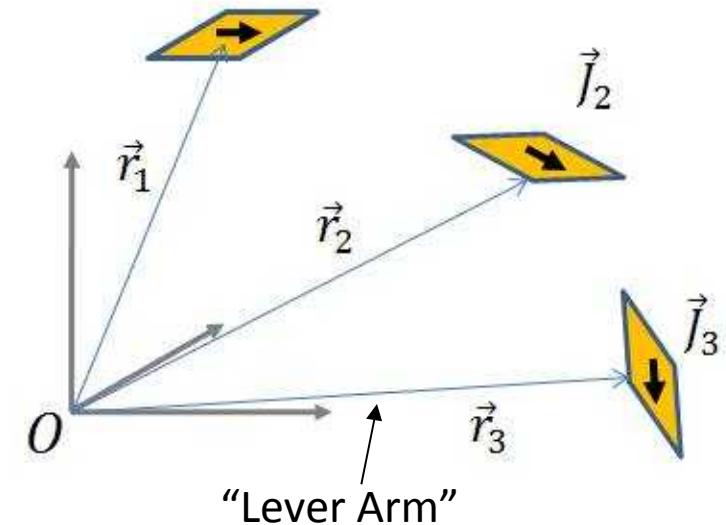
Magnetic Field

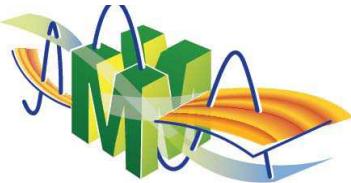
$$B(x, y, z) = \frac{\mu_0 I}{4\pi} \sum \left(\frac{dl' \times \vec{R}}{|R|^3} \right)$$



Magnetization Vector

$$\vec{M} \equiv \frac{1}{2c} \sum \vec{r}_i \times \vec{J}_i$$





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Magnetization Vector

$$\vec{M} \equiv \frac{1}{2c} (\vec{r} \times \vec{J})$$

Bulk Material Property

$$\vec{H} = \frac{1}{\mu} \vec{B}$$

$$\vec{H} = \vec{B} - 4\pi \vec{M}$$

Nano Antenna Property

$$A(\vec{r}) = \text{Dipole Term} + C \int J(\vec{r}) (\vec{n} \cdot \vec{r})$$

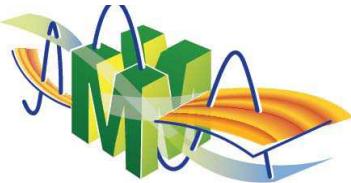
Electric
Quadrupole
Term

Magnetic
Dipole
Term

$$\frac{1}{2c} [(\vec{n} \cdot \vec{r}) \vec{J} + (\vec{n} \cdot \vec{J}) \vec{r}] + \frac{1}{2c} (\vec{r} \times \vec{J}) \times \vec{n}$$

$$\vec{M}$$

Both the material parameter μ and the far-field scattering behavior depend on the magnetization vector of the meta – “atoms”.

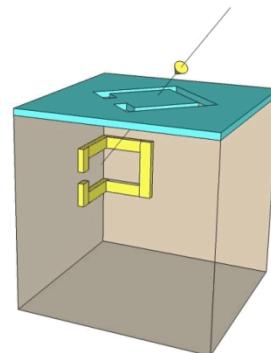
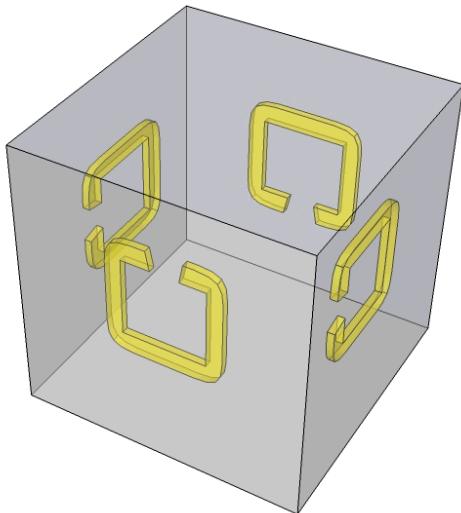


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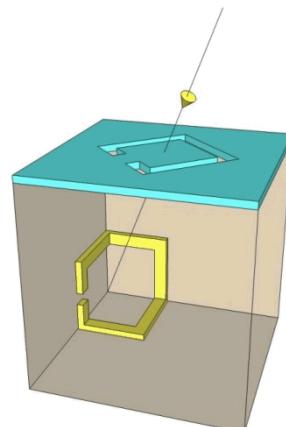
MPL Enables Truly 3-D Resonators

3-D Could Be or 2.5-D

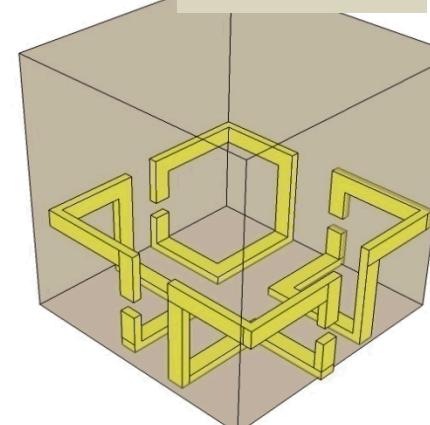
3-D Array of
Planar SRRs



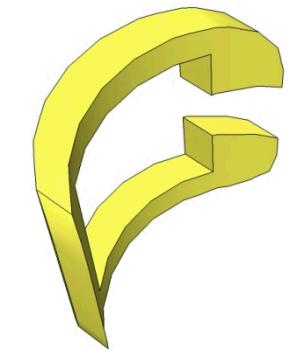
3-D Array of
2-D SRRs



3-D Array of
3-D SRRs



Cylindrical



Spherical

